

EAST Search History


Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L9	8	(local near flare).cm.	US-PGPUB	OR	ON	2009/05/19 15:33

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L6	132	703/6.ccls. and @pd>="20081101"	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2009/05/19 14:39
L7	68	(local near flare)	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2009/05/19 15:05

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S16	1953	716/19.ccls.	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2009/05/19 15:57


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Local flare effects and correction in ArF lithography

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Page 1. 4B-1 **Local Flare** Effects and Correction in ArF Lithography Teruyoshi Yao, Morimi Osawa, Takayoshi M ind , Norihiro Yamamoto, Hajime Aoyama, ...

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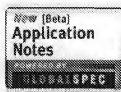
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